

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

JC929 U.S. PRO  
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In re New Patent Application of )  
Shigeo IRIE )  
Japanese Priority Application No. 2000-192459 ) Attn: Applications  
Japanese Priority Date: June 27, 2000 ) Branch  
For: PATTERN FORMING METHOD AND )  
APPARATUS FOR FABRICATING )  
SEMICONDUCTOR DEVICE ) Date: June 26, 2001

*HJ  
D,6 -  
9-21-01*

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents  
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the reference listed on the attached Form PTO-1449 be made of record in the above-identified application.

A copy of this reference is submitted herewith in accordance with 37 C.F.R. 1.98(a).

Respectfully submitted,

  
Eric J. Robinson  
Registration No. 38,285

NIXON PEABODY LLP  
8180 Greensboro Drive, Suite 800  
McLean, Virginia 22102  
(703) 790-9110